



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

pplicant(s):

T. HIROSE, et al.

Serial No.:

09/800,495

Filed:

March 8, 2001

For:

METHOD OF DETECTING AND MEASURING ENDPOINT OF POLISHING PROCESSING AND ITS APPARATUS AND

METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

USING THE SAME

Group:

1765

Examiner:

L. Umez Eronini

<u>PETITION FOR EXTENSION OF TIME</u>

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

July 1, 2004

Sir:

In the matter of the above-identified application, applicant(s) hereby respectfully petition for an extension of time to permit filing of a response within the first month subsequent to the shortened statutory period set in the outstanding Office Action mailed March 3, 2004. A payment in the amount of \$110.00 to cover the required fee for the requested extension of time is attached hereto.

It is respectfully requested that any shortage in the fee be charged to the account of Antonelli, Terry, Stout & Kraus, LLP, Account No. 01-2135 (500.39825X00).

07/06/2004 AADDFD1 00000048 09800495

Respectfully submitted,

01 FC:1251

110.00 OP

Registration No. 22,466

ANTONELLI, TERRY, STOUT & KRAUS, LLP

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